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**EE C247B - ME C218**  
**Introduction to MEMS Design**  
**Spring 2020**


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**Lecture Module 15: Gyros, Noise, & MDS**

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**Lecture Outline**

- Reading: Senturia, Chpt. 14, Chpt. 16, Chpt. 21
- Lecture Topics:
  - ↗ Gyroscopes
  - ↗ Gyro Circuit Modeling
  - ↗ Minimum Detectable Signal (MDS)
    - Noise
    - Angle Random Walk (ARW)

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## Gyroscopes

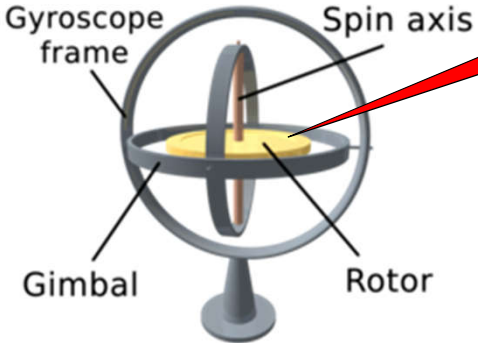
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### Classic Spinning Gyroscope

- A gyroscope measures rotation rate, which then gives orientation → very important, of course, for navigation
- Principle of operation based on conservation of momentum
- Example: classic spinning gyroscope



Rotor will preserve its angular momentum (i.e., will maintain its axis of spin) despite rotation of its gimbed chassis



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### Vibratory Gyroscopes

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- Generate momentum by vibrating structures
- Again, conservation of momentum leads to mechanisms for measuring rotation rate and orientation
- **Example:** vibrating mass in a rotating frame

Mass at rest

Driven into vibration along the y-axis

Rotate 30°

Get an  $x'$  component of motion

$C(t_2) > C(t_1)$

Capacitance between mass and frame = constant

y-displaced mass

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### Basic Vibratory Gyroscope Operation

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**Principle of Operation**

- Tuning Fork Gyroscope:

Input Rotation  $\vec{\Omega}$

Driven Vibration @  $f_0$

Coriolis (Sense) Response

Coriolis Torque

Detect motion out-of-the plane of the tuning fork as rotation!

Side View:

Top View:

Post

Support

Support = 0

not force on support

very little anchor dissipation

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### Basic Vibratory Gyroscope Operation

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**Principle of Operation**

- Tuning Fork Gyroscope:

Input Rotation  $\vec{\Omega}$

Driven Vibration @  $f_o$

Driven Velocity  $\vec{v}$

Coriolis (Sense) Response  $\vec{a}_c$

Coriolis Torque

Coriolis Force  $\vec{F}_c$

Coriolis Displacement  $\vec{x}$

Beam Mass

Beam Stiffness (in sense direction)  $k$

Sense Frequency  $\omega_r$

Rotation Rate  $\vec{\Omega}$

Driven Velocity  $\vec{v}$

Coriolis Acceleration  $\vec{a}_c = 2\vec{v} \times \vec{\Omega}$

Coriolis Force  $\vec{F}_c = m\vec{a}_c$

Coriolis Displacement  $\vec{x} = \frac{\vec{F}_c}{k} = \frac{m\vec{a}_c}{k} = \frac{\vec{a}_c}{\omega_r^2}$

**Drive/Sense Response Spectra:**

Amplitude

Drive Response

Sense Response

$f_o$  (@  $T_1$ )

$\omega$

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### Vibratory Gyroscope Performance

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**Principle of Operation**

- Tuning Fork Gyroscope:

Input Rotation  $\vec{\Omega}$

Driven Vibration @  $f_o$

Driven Velocity  $\vec{v}$

Coriolis (Sense) Response  $\vec{a}_c$

Coriolis Torque

Beam Mass

Beam Stiffness  $k$

Sense Frequency  $\omega_r$

Driven Velocity  $\vec{v}$

Coriolis Acceleration  $\vec{a}_c = 2\vec{v} \times \vec{\Omega}$

Coriolis Force  $\vec{F}_c = m\vec{a}_c$

Coriolis Displacement  $\vec{x} = \frac{\vec{F}_c}{k} = \frac{m\vec{a}_c}{k} = \frac{\vec{a}_c}{\omega_r^2}$

**To maximize the output signal  $x$ , need:**

- ↙ Large sense-axis mass
- ↙ Small sense-axis stiffness
- (Above together mean low resonance frequency)
- ↙ Large drive amplitude for large driven velocity (so use comb-drive)
- ↙ If can match drive freq. to sense freq., then can amplify output by Q times

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**MEMS-Based Gyroscopes**

The slide displays three types of MEMS-based gyroscopes:

- Tuning Fork Gyroscope [Ayazi, GA Tech.]:** A top-down view of a cross-shaped structure with a central post and four proof masses.
- Vibrating Ring Gyroscope [Najafi, Michigan]:** A circular ring structure with radial spokes and a central hub.
- Nuclear Magnetic Resonance Gyro [NIIST]:** A 3D perspective view of a rectangular device with a laser, polarizer, Rb/Xe cell, and photodiode. Dimensions are 3.2 mm by 1 mm by 1 mm. It shows a rotation rate  $\dot{\theta}$ .

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**MEMS-Based Tuning Fork Gyroscope**

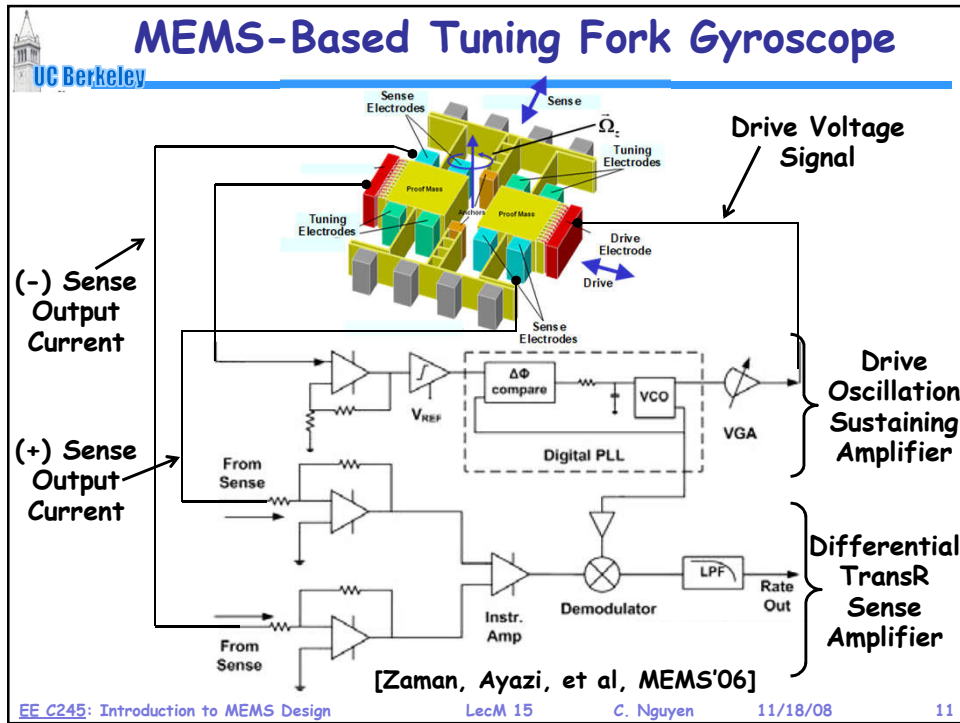
The diagram illustrates the components and operation of a MEMS-based tuning fork gyroscope:

- Components:** Sense Electrodes, Drive Electrode, Tuning Electrodes, Proof Mass, Anchors, Quadrature Cancellation Electrodes, and Sense Electrodes.
- Drive Mode:** Shows the proof masses oscillating in the horizontal plane.
- Sense Mode:** Shows the proof masses oscillating in the vertical plane, detecting rotation.

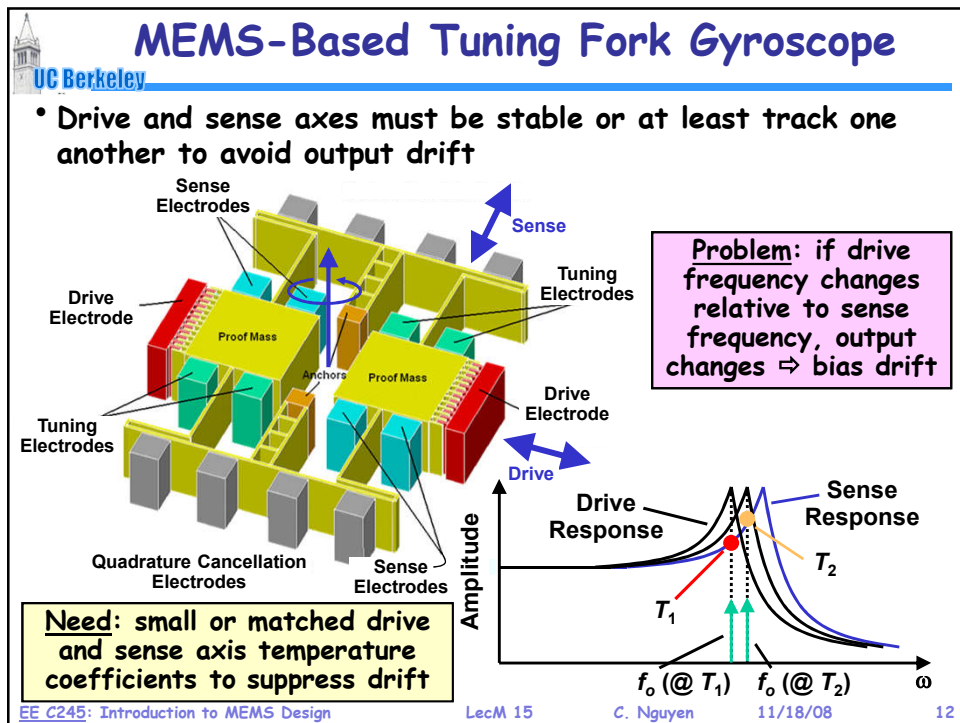
- In-plane drive and sense modes pick up z-axis rotations
- Mode-matching for maximum output sensitivity
- From [Zaman, Ayazi, et al, MEMS'06]

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### Mode Matching for Higher Resolution

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- For higher resolution, can try to match drive and sense axis resonance frequencies and benefit from Q amplification

**Problem:** mismatch between drive and sense frequencies  $\Rightarrow$  even larger drift!

**Need:** small or matched drive and sense axis temperature coefficients to make this work

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### Issue: Zero Rate Bias Error

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- Imbalances in the system can lead to zero rate bias error

Drive imbalance  $\Rightarrow$  off-axis motion of the proof mass

Output signal in phase with the Coriolis acceleration

Mass imbalance  $\Rightarrow$  off-axis motion of the proof mass

Quadrature output signal that can be confused with the Coriolis acceleration

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### Nuclear Magnetic Res. Gyroscope

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- The ultimate in miniaturized spinning gyroscopes?
  - ↳ from CSAC, we may now have the technology to do this

Better if this is a noble gas nucleus (rather than e-), since nuclei are heavier  $\Rightarrow$  less susceptible to B field

Soln: Spin polarize Xe<sup>129</sup> nuclei by first polarizing e- of Rb<sup>87</sup> (a la CSAC), then allowing spin exchange

**Challenge:** suppressing the effects of B field

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### MEMS-Based Tuning Fork Gyroscope

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[Zaman, Ayazi, et al, MEMS'06]

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## Determining Sensor Resolution

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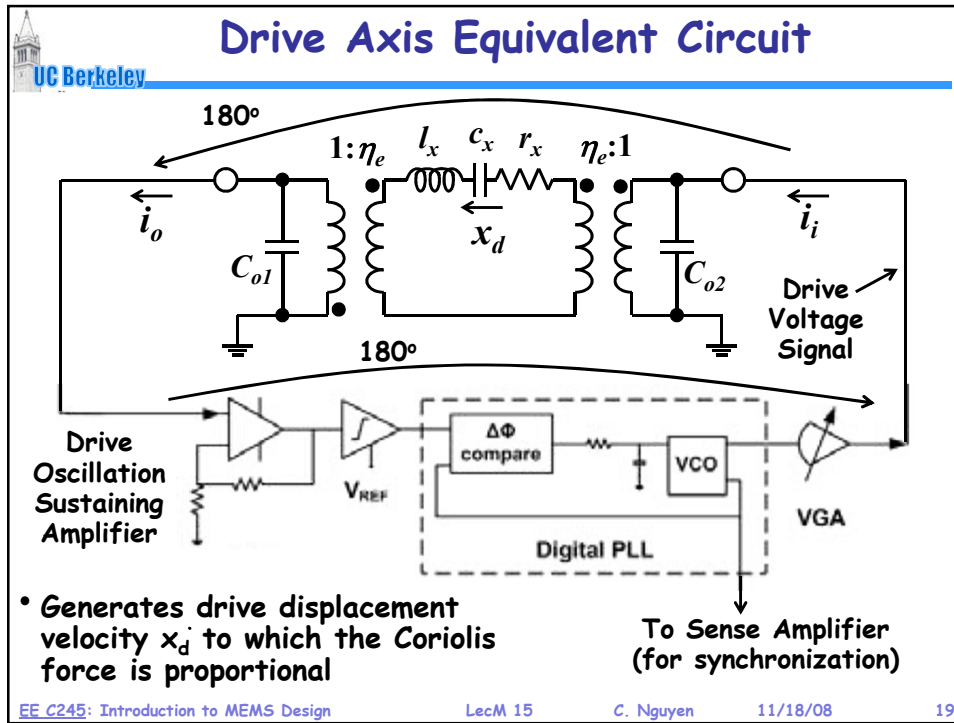
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## MEMS-Based Tuning Fork Gyroscope

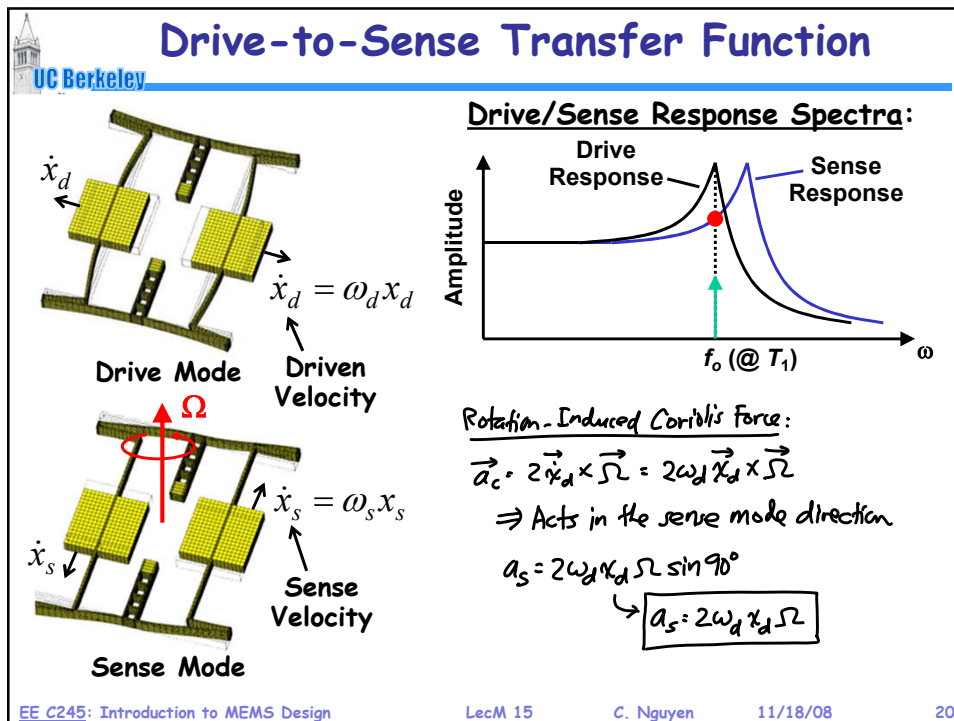
[Zaman, Ayazi, et al, MEMS'06]

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### Gyro Readout Equivalent Circuit (for a single tine)

$\vec{F}_c = m\vec{a}_c = m \cdot (2\vec{\dot{x}}_d \times \vec{\Omega})$

**Noise Sources**

**Gyro Sense Element Output Circuit**

**Signal Conditioning Circuit (Transresistance Amplifier)**

- Easiest to analyze if all noise sources are summed at a common node

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### Minimum Detectable Signal (MDS)

- **Minimum Detectable Signal (MDS):** Input signal level when the signal-to-noise ratio (SNR) is equal to unity

**Sensor**

**Signal Conditioning Circuit**

**Output**  
Includes desired output plus noise

- The sensor scale factor is governed by the sensor type
- The effect of noise is best determined via analysis of the equivalent circuit for the system

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**Move Noise Sources to a Common Point**

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- Move noise sources so that all sum at the input to the amplifier circuit (i.e., at the output of the sense element)
- Then, can compare the output of the sensed signal directly to the noise at this node to get the MDS

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**Gyro Readout Equivalent Circuit (for a single tone)**

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Noise Sources

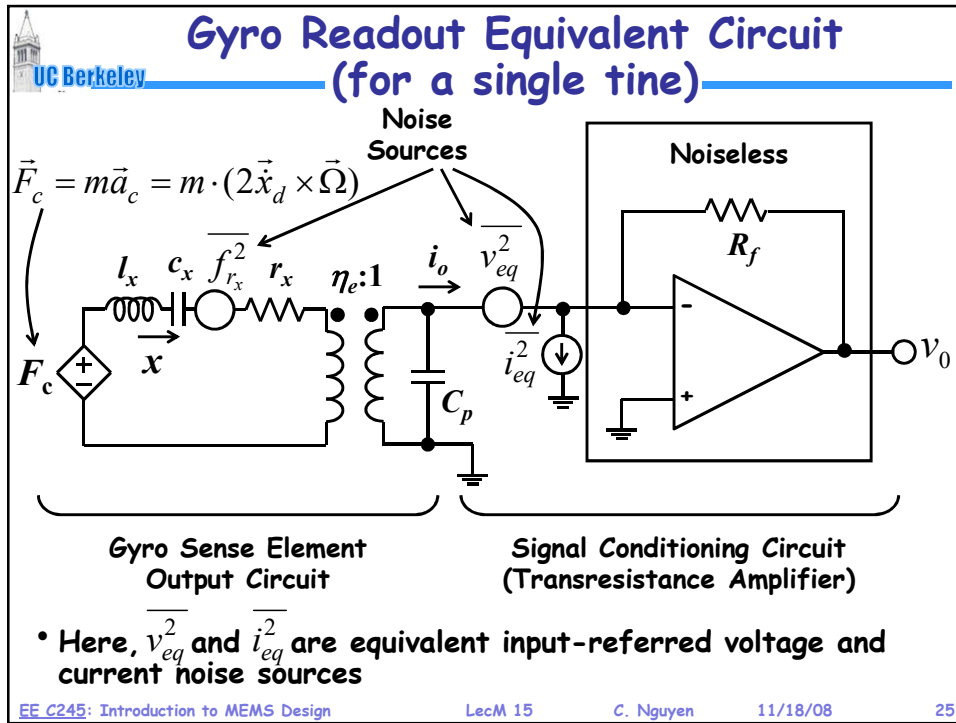
$$\vec{F}_c = m\vec{a}_c = m \cdot (2\vec{\dot{x}}_d \times \vec{\Omega})$$

Gyro Sense Element Output Circuit      Signal Conditioning Circuit (Transresistance Amplifier)

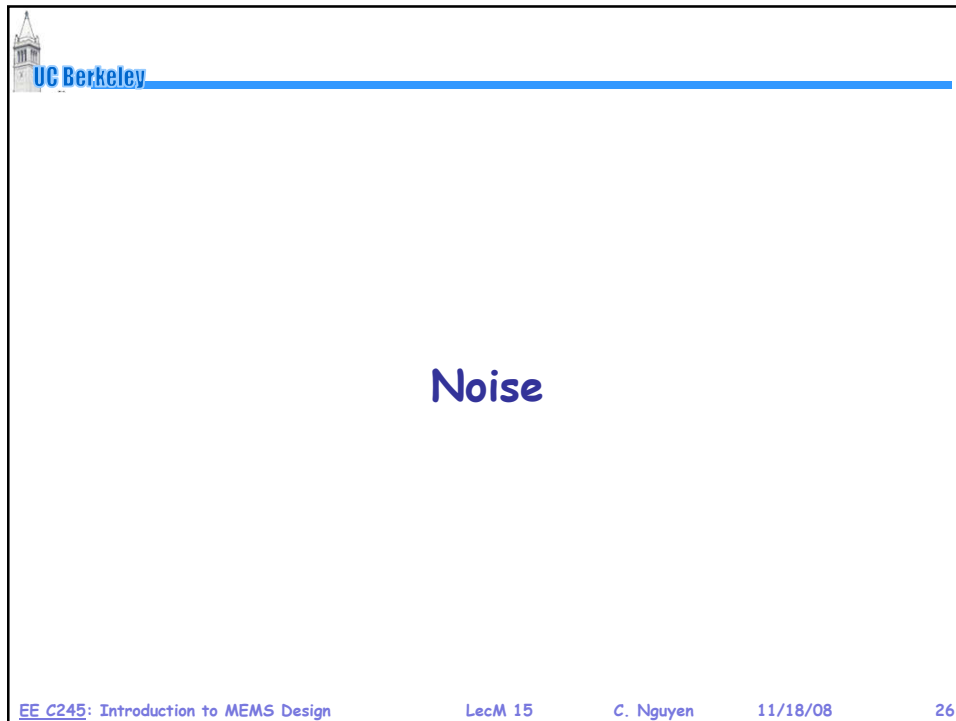
- Easiest to analyze if all noise sources are summed at a common node

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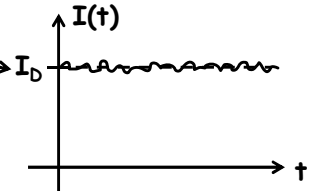


## Noise

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- **Noise:** Random fluctuation of a given parameter  $I(t)$
- In addition, a noise waveform has a zero average value

Avg. value  
(e.g. could be DC current)




- We can't handle noise at instantaneous times
- But we can handle some of the averaged effects of random fluctuations by giving noise a power spectral density representation
- Thus, represent noise by its mean-square value:

Let  $i(t) = I(t) - I_D$

Then  $\overline{i^2} = \overline{(I - I_D)^2} = \lim_{T \rightarrow \infty} \frac{1}{T} \int_0^T |I - I_D|^2 dt$

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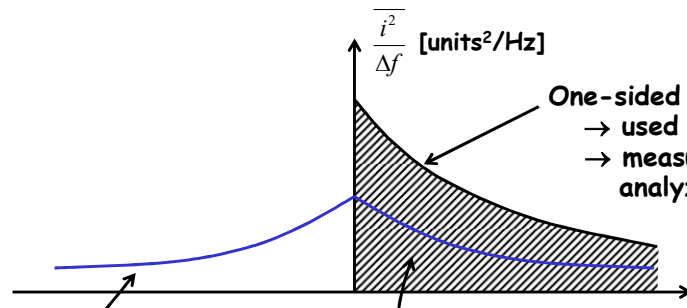
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## Noise Spectral Density

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- We can plot the spectral density of this mean-square value:



$\frac{\overline{i^2}}{\Delta f}$  [units<sup>2</sup>/Hz]

One-sided spectral density  
 → used in circuits  
 → measured by spectrum analyzers

Two-sided spectral density  
 (1/2 the one-sided)  
 Often used in systems courses

$\overline{i^2} =$  integrated mean-square noise spectral density over all frequencies (area under the curve)

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### Circuit Noise Calculations

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The diagram shows a block labeled "Linear Time-Invariant System" with transfer function  $H(j\omega)$ . It has two input paths: "Deterministic" with input  $v_i(j\omega)$  and "Random" with input  $S_i(\omega)$ . It has two output paths: "Deterministic" with output  $v_o(j\omega)$  and "Random" with output  $S_o(\omega)$ . Handwritten notes include "No  $j \rightarrow$  noise has random phase, so  $j$  is pointless!".

Two plots illustrate the outputs:
 

- Deterministic:** A sinusoidal waveform  $v_o(t)$  with period  $\frac{2\pi}{\omega_o}$  is shown next to its spectral density plot  $v_o(j\omega)$ , which has a single peak at  $\omega_o$ .
- Random:** A noisy waveform  $S_o(t)$  is shown next to its spectral density plot  $S_o(j\omega)$ , which shows a continuous distribution of power around  $\omega_o$ .

 The label "Mean square spectral density" is associated with the random output plots.

- **Deterministic:**  $v_o(j\omega) = H(j\omega)v_i(j\omega)$
- **Random:**  $S_o(\omega) = [H(j\omega)H^*(j\omega)]S_i(\omega) = |H(j\omega)|^2 S_i(\omega)$

$\sqrt{S_o(\omega)} = |H(j\omega)|\sqrt{S_i(\omega)}$   $\longrightarrow$  How is it we can do this?  
 Root mean square amplitudes

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### Handling Noise Deterministically

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- Can do this for noise in a tiny bandwidth (e.g., 1 Hz)

The diagram illustrates the process of approximating noise in a narrow bandwidth  $B$  around a center frequency  $\omega_o$ . It shows a spectral density plot  $S_1(f)$  with a small interval  $B$  highlighted. This is approximated by a sinusoidal voltage generator  $v_o(t) = |A| \cos \omega_o t$  with amplitude  $|A|$  and period  $\tau \sim \frac{1}{B}$ . A block diagram shows the noise source  $S_n(j\omega)$  passing through a filter with gain  $\frac{|S_o|}{|S_i|}$  and bandwidth  $B$  to produce the sinusoidal output.

Can approximate this by a sinusoidal voltage generator (especially for small  $B$ , say 1 Hz)

[This is actually the principle by which oscillators work  $\rightarrow$  oscillators are just noise going through a tiny bandwidth filter]

Why? Neither the amplitude nor the phase of a signal can change appreciably within a time period  $1/B$ .

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**Systematic Noise Calculation Procedure**  
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General Circuit With Several Noise Sources

- Assume noise sources are uncorrelated
- 1. For  $\overline{i_{n1}^2}$  replace w/ a deterministic source of value
 
$$i_{n1} = \sqrt{\frac{\overline{i_{n1}^2}}{\Delta f}} \cdot (1 \text{ Hz})$$

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**Systematic Noise Calculation Procedure**  
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- Calculate  $v_{on1}(\omega) = i_{n1}(\omega)H(j\omega)$  (treating it like a deterministic signal)
- Determine  $\overline{v_{on1}^2} = \overline{i_{n1}^2} \cdot |H(j\omega)|^2$
- Repeat for each noise source:  $\overline{i_{n1}^2}, \overline{v_{n2}^2}, \overline{v_{n3}^2}$
- Add noise power (mean square values)
 
$$\overline{v_{onTOT}^2} = \overline{v_{on1}^2} + \overline{v_{on2}^2} + \overline{v_{on3}^2} + \overline{v_{on4}^2} + \dots$$

$$v_{onTOT} = \sqrt{\overline{v_{on1}^2} + \overline{v_{on2}^2} + \overline{v_{on3}^2} + \overline{v_{on4}^2} + \dots}$$

↑  
Total rms value

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## Determining Sensor Resolution

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### Example: Gyro MDS Calculation

$$\vec{F}_c = m\vec{a}_c = m \cdot (2\vec{\dot{x}}_d \times \vec{\Omega})$$

- The gyro sense presents a large effective source impedance
  - ↳ Currents are the important variable; voltages are "opened" out
  - ↳ Must compare  $i_o$  with the total current noise  $i_{eqTOT}$  going into the amplifier circuit

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### Example: Gyro MDS Calculation (cont)

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$$\vec{F}_c = m\vec{a}_c = m \cdot (2\vec{\dot{x}}_d \times \vec{\Omega})$$

$$i_o = v_{eq}^2 \cdot \frac{1}{\omega_s^2}$$

• First, find the rotation to  $i_o$  transfer function:

$$\dot{x}_s = \frac{\omega_s Q}{k_s} \Theta_s(j\omega_d) F_s = \frac{\omega_s Q}{k_s} \cdot 2\omega_d \kappa_d \Omega m \cdot \Theta(j\omega_d)$$

$$[F_s = F_c = 2\omega_d \kappa_d \Omega m] \quad \downarrow \quad \frac{1}{\omega_s^2}$$

$$\dot{x}_s = 2 \frac{\omega_d}{\omega_s} Q \kappa_d \Theta(j\omega_d) \cdot \Omega$$

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### Example: Gyro MDS Calculation (cont)

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$$i_o = \eta_e \dot{x}_s = 2 \frac{\omega_d}{\omega_s} Q \kappa_d \eta_e \Theta(j\omega_d) \cdot \Omega \Rightarrow i_o = A \Omega$$

$A \triangleq$  scale factor

$$\text{Where } A = 2 \frac{\omega_d}{\omega_s} Q \kappa_d \eta_e \Theta(j\omega_d)$$

When  $\Omega = \Omega_{min} \triangleq$  MDS,  $i_o = i_{eqTOT}$  ← input-referred noise current entering the sense amplifier → in pA/√Hz

$$\therefore i_{eqTOT} = A \Omega_{min} \rightarrow \Omega_{min} = \frac{i_{eqTOT}}{A} \left( \frac{3600s}{hr} \right) \left( \frac{180^\circ}{\pi} \right) \left[ \left( \frac{\%}{hr} \right) / \sqrt{Hz} \right]$$

$$\text{Angle Random Walk: ARW} = \frac{1}{60} \Omega_{min} \left[ \frac{\circ}{\sqrt{hr}} \right]$$

↪ Easier to determine directional error as a function of elapsed time.

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**Example: Gyro MDS Calculation (cont)**

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$\vec{F}_c = m\vec{a}_c = m \cdot (2\vec{\dot{x}}_d \times \vec{\Omega})$

• Now, find the  $i_{eqTOT}$  entering the amplifier input:

$$i_{eqTOT}^2 = i_s^2 + i_{eq}^2 \rightarrow i_{eqTOT}^2 = i_s^2 + i_f^2 + i_{ia}^2 + \frac{N_{ia}^2}{R_f^2}$$

$\frac{f_{rx}^2}{\Delta f} = 4kTR_x$

Brownian motion noise of the sense element  $\rightarrow$  determined entirely by the noise in  $r_x \rightarrow f_{rx}^2$   
 $\hookrightarrow$  easiest to convert to an all electrical equiv. ckt.

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**Example: Gyro MDS Calculation (cont)**

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Where  $L_x = \frac{I_x}{\eta_e}$ ,  $C_x = \eta_e^2 C_x$ ,  $R_x = \frac{r_x}{\eta_e}$

$$\therefore i_s = N_{R_x} \left( \frac{1}{R_x} \right) \oplus(j\omega_d) \rightarrow \frac{i_s^2}{\Delta f} = 4kTR_x \left( \frac{1}{R_x^2} \right) |\oplus(j\omega_d)|^2$$

$$\Rightarrow \frac{i_s^2}{\Delta f} = \frac{4kT}{R_x} |\oplus(j\omega_d)|^2$$

Thus:

$$\frac{i_{eqTOT}^2}{\Delta f} = \frac{4kT}{R_x} |\oplus(j\omega_d)|^2 + \frac{4kT}{R_f} + \frac{i_{ia}^2}{\Delta f} + \frac{N_{ia}^2}{\Delta f} \left( \frac{1}{R_f^2} \right)$$

Learn to get there from EE240.  
 $\hookrightarrow$  or just get them from a data sheet ...

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## LF356 Op Amp Data Sheet

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### LF155/LF156/LF256/LF257/LF355/LF356/LF357 JFET Input Operational Amplifiers

**General Description**  
 These are the first monolithic JFET input operational amplifiers to incorporate well matched, high voltage JFETs on the same chip with standard bipolar transistors (BI-FET™ Technology). These amplifiers feature low input bias and offset currents/low offset voltage and offset voltage drift, coupled with offset adjust which does not degrade drift or common-mode rejection. The devices are also designed for high slew rate, wide bandwidth, extremely fast settling time, low voltage and current noise and a low 1/f noise corner.

**Common Features**

- Logarithmic amplifiers
- Photocell amplifiers
- Sample and Hold circuits
- Low input bias current: 30pA
- Low Input Offset Current: 3pA
- High input impedance:  $10^{12}\Omega$
- Low input noise current:  $0.01 \text{ pA}/\sqrt{\text{Hz}}$
- High common-mode rejection ratio: 100 dB
- Large dc voltage gain: 106 dB

**Features**

**Advantages**

- Replace expensive hybrid and module FET op amps
- Rugged JFETs allow blow-out free handling compared with MOSFET input devices
- Excellent for low noise applications using either high or low source impedance—very low 1/f corner
- Offset adjust does not degrade drift or common-mode rejection as in most monolithic amplifiers
- New output stage allows use of large capacitive loads (5,000 pF) without stability problems
- Internal compensation and large differential input voltage capability

**Applications**

- Precision high speed integrators
- Fast D/A and A/D converters
- High impedance buffers
- Wideband, low noise, low drift amplifiers

**Uncommon Features**

	LF155/ LF355	LF156/ LF256/ LF356	LF257/ LF357 ( $A_V=5$ )	Units
Extremely fast settling time to 0.01%	4	1.5	1.5	$\mu\text{s}$
Fast slew rate	5	12	50	V/ $\mu\text{s}$
Wide gain bandwidth	2.5	5	20	MHz
Low input noise voltage	20	12	12	nV/ $\sqrt{\text{Hz}}$

*Handwritten notes:*  
 $\sqrt{\frac{0.01 \text{ pA}}{\Delta f}} = 0.01 \text{ pA}/\sqrt{\text{Hz}}$   
 $\sqrt{\frac{12 \text{ nV}}{\Delta f}} = 12 \text{ nV}/\sqrt{\text{Hz}}$

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## Example ARW Calculation

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**• Example Design:**

**↳ Sensor Element:**

$m = (100\mu\text{m})(100\mu\text{m})(20\mu\text{m})(2300\text{kg}/\text{m}^3) = 4.6 \times 10^{-10}\text{kg}$

$\omega_s = 2\pi(15\text{kHz})$

$\omega_d = 2\pi(10\text{kHz})$

$k_s = \omega_s^2 m = 4.09 \text{ N/m}$

$x_d = 20 \mu\text{m}$

$Q_s = 50,000$

$V_p = 5\text{V}$

$h = 20 \mu\text{m}$

$d = 1 \mu\text{m}$

**↳ Sensing Circuitry:**

$R_f = 100\text{k}\Omega$

$i_{ia} = 0.01 \text{ pA}/\sqrt{\text{Hz}}$

$v_{ia} = 12 \text{ nV}/\sqrt{\text{Hz}}$

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**Example ARW Calculation (cont)**

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Get rotation rate to output current scale factor:

$$A = 2 \frac{\omega_d}{\omega_s} Q_s \eta_e \eta_e |\Phi(j\omega_d)| = 2 \left( \frac{10k}{15k} \right) (50k) (20\mu) (5) (2000 \epsilon_0) (0.000024) = 2.83 \times 10^{-12} C$$

$$\left[ \Phi(j\omega_d) = \frac{(j\omega_d)(\omega_s/\omega_s)}{-\omega_d^2 + \frac{j\omega_d \omega_s}{Q_s} + \omega_s^2} = \frac{j(10k)(15k)/(50k)}{(15k)^2 - (10k)^2 + \frac{j(10k)(15k)}{50k}} = \frac{j(3k)}{1.25 \times 10^8 + j(3k)} \right]$$

$$\Rightarrow |\Phi(j\omega_d)| = \frac{3k}{\sqrt{(1.25 \times 10^8)^2 + (3k)^2}} = 0.000024 \quad 8.854 \times 10^{-8} F/m$$

$$\left[ \frac{\partial C}{\partial x} = \frac{C_0}{d} = \frac{\epsilon_0 h \omega_p}{d} = \frac{\epsilon_0 (20\mu)(100\mu)}{(1\mu)^2} = 2000 \epsilon_0 \rightarrow \eta_e = V_p \frac{\partial C}{\partial x} = 5(2000 \epsilon_0) \quad 8.854 \times 10^{-12} F/m \right]$$

Assume electrode covers the whole sidewall.

Then, get noise:

$$\frac{\overline{i_{eq}^2}}{\Delta f} = \frac{4kT}{R_x} |\Phi(j\omega_d)|^2 + \frac{4kT}{R_f} + \frac{\overline{i_{ia}^2}}{\Delta f} + \frac{\overline{N_{ie}^2}}{\Delta f} \left( \frac{1}{R_f} \right)$$

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**Example ARW Calculation (cont)**

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$$\left[ R_x = \frac{\omega_s m}{Q_s \eta_e^2} = \frac{2\pi(15k)(4.6 \times 10^{-10})}{(50k)(8.854 \times 10^{-8})^2} = 110.6 k\Omega \right]$$

$$\frac{\overline{i_{eqTOT}^2}}{\Delta f} = \frac{(1.66 \times 10^{-29})}{(110.6k)} (0.000024)^2 + \frac{(1.66 \times 10^{-29})}{1M} + (0.01p)^2 + \frac{(12n)^2}{(1M)^2}$$

$\rightarrow 8.64 \times 10^{-35} A^2/Hz$        $1.66 \times 10^{-26} A^2/Hz$        $1 \times 10^{-28} A^2/Hz$        $1.44 \times 10^{-28} A^2/Hz$   
 sensor element noise      Noise from  $R_f$  dominates!  
 insignificant

$$\therefore \frac{\overline{i_{eqTOT}^2}}{\Delta f} = 1.68 \times 10^{-26} A^2/Hz \rightarrow i_{eqTOT} = \sqrt{\frac{\overline{i_{eqTOT}^2}}{\Delta f}} = 1.30 \times 10^{-13} A/\sqrt{Hz}$$

$$\therefore \Omega_{min} = \frac{i_{eqTOT}}{A} \left( \frac{3600s}{hr} \right) \left( \frac{180^\circ}{\pi} \right) = \frac{1.30 \times 10^{-13}}{2.83 \times 10^{-12}} (3600) \left( \frac{180}{\pi} \right) = 9448 (\%hr)/\sqrt{Hz}$$

And finally:

$$ARW = \frac{1}{60} \Omega_{min} = \frac{1}{60} (9448) = 157 \%hr = ARW \Rightarrow \text{Almost turned around in 1 hour!}$$

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**What if  $\omega_d = \omega_s$ ?**

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If  $\omega_d = \omega_s = 15\text{kHz}$ , then  $|\Phi(j\omega_d)| = 1$  and

$$A = 2 \frac{\omega_d}{\omega_s} Q_s X_d \eta_e |\Phi(j\omega_d)| = 2 Q_s X_d \eta_e = 2(50k)(20\mu)(5)(2000e_0) = 1.77 \times 10^{-7} \text{C}$$

$$\frac{\dot{i}_{eqTOT}^2}{\Delta f} = \frac{(1.66 \times 10^{-29})^2}{(110.6k)^2} + \frac{(1.66 \times 10^{-29})^2}{1M} + (0.01p)^2 + \frac{(12n)^2}{(1M)^2}$$

$\swarrow 1.51 \times 10^{-25} \text{A}^2/\text{Hz}$    
  $\swarrow 1.66 \times 10^{-26} \text{A}^2/\text{Hz}$    
  $\swarrow 1 \times 10^{-28} \text{A}^2/\text{Hz}$    
  $\swarrow 1.44 \times 10^{-28} \text{A}^2/\text{Hz}$

Now, the sensor element dominates!

$$\therefore \frac{\dot{i}_{eqTOT}^2}{\Delta f} = 1.67 \times 10^{-25} \text{A}^2/\text{Hz} \rightarrow \dot{i}_{eqTOT} = \sqrt{\frac{\dot{i}_{eqTOT}^2}{\Delta f}} = 4.08 \times 10^{-13} \text{A}/\sqrt{\text{Hz}}$$

$$\therefore \Sigma_{min} = \frac{\dot{i}_{eqTOT}}{A} \left( \frac{3600s}{hr} \right) \left( \frac{180^\circ}{\pi} \right) = \frac{4.08 \times 10^{-13}}{1.77 \times 10^{-7}} (3600) \left( \frac{180}{\pi} \right) = 0.476 (\%/hr)/\sqrt{\text{Hz}}$$

And finally:

$$ARW = \frac{1}{60} \Sigma_{min} = \frac{1}{60} (0.476) = 0.0079 \%/hr = ARW \Rightarrow \text{Navigation grade!}$$

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